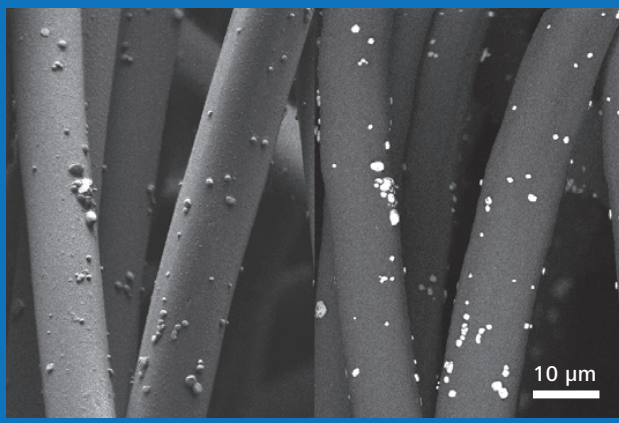


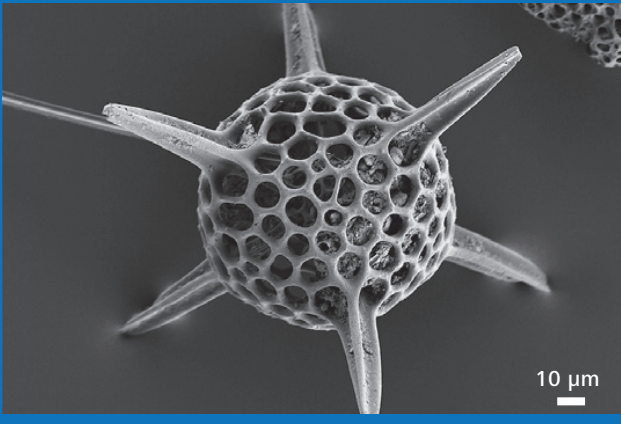
Advanced alloy material imaged at 3 kV in high vacuum shows the tungsten core material surrounded by a steel matrix.



Fibres with embedded silver nanoparticles, 1 kV, left: InLens Duo SE, right: InLens Duo BSE. Originate from antimicrobial dressings in wound care.



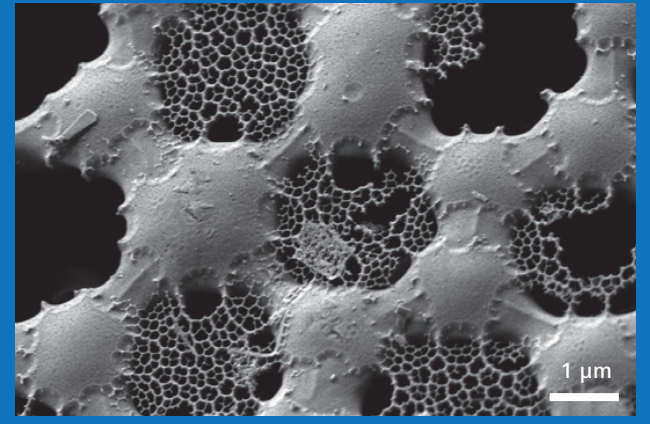
Lanthanum carbonate imaged at 1 kV with InLens Duo BSE. LaCO<sub>3</sub> is a phosphate binder used as a oral therapeutic agent for dialysis patients.



The delicate open structure of a radiolarian is imaged effortlessly by the ETSE detector at 1 kV under high vacuum.



Fine filtered, mixed sediment imaged with the ETSE under high vacuum at 3 kV.



The delicate open structure of a non-conductive diatom can be imaged at low kV in high vacuum without charging artefacts with the ETSE.

## LEARN ABOUT:

- LM to LSM Confocal: ZEISS LSM 900 with Airyscan
- SEM to FESEM and Operations: Sigma 300 with EDS, Sputter Coater & CPD
- Digital Image Analysis & Workflow Platform – APEER
- Hands on demo on Sigma 300 with EDS



## WORKSHOP

# Recent Trends Of Microscopy: Light To Electron Microscopy & Digital Image Analysis

### 19 - 20 SEPTEMBER 2019

## WORKSHOP & DEMO:

Faculty from Central Instrumentation Centre, Tripura University

&

Technical & Application Specialists from ZEISS India

## VENUE:

Department of Physics, Tripura University, Agartala  
Central Instrumentation Centre, Tripura University, Agartala

## TO KNOW MORE, CONTACT:

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Convener, Central Instrumentation Centre, Tripura University  
Ph. No.: +91 940212 2510 | E-Mail ID: sahussain@tripurauniv.in



in association with



# WORKSHOP on Recent Trends of Microscopy: Light To Electron Microscopy & Digital Image Analysis

19 - 20 SEPTEMBER 2019

## Lecture details:

### **Lecture 1:**

#### **New Approaches of Light Microscopy to Break Resolution Limitations**

By Dr. Anupam Banerjee,  
Application Specialist, LM & LSM  
Zeiss India

### **Lecture 2:**

#### **Basics of SEM & FESEM Technology and It's Applications in Various Research Fields**

By Mr. Shibasis Chatterjee,  
Application Specialist, EM  
Zeiss India

### **Lecture 3:**

#### **Sample Preparation for SEM/ FESEM**

By Mr. Shibasis Chatterjee,  
Application Specialist, EM  
Zeiss India

### **Lecture 4:**

#### **Knowhow about Digital Image Analysis Platform - It's Importance and Scope**

By Dr. Anupam Banerjee,  
Application Specialist, LM & LSM  
Zeiss India

### **Demonstration:**

#### **Hands On Live Demo on Zeiss FE-SEM Model Sigma 300 with EDS**

By Mr. Shibasis Chatterjee and Mr. Tridib Das  
Zeiss India

## **Instruction for attending the workshop:**

**Target participants:** Research scholars, M.Tech/PG students and faculty members.

Maximum number of participants: **35**

Participants must send the filled up registration form (given below) latest by **10.09.2019** by email at **cic@tripurauniv.in**

### **Registration fee:**

Research Scholars / students: Rs 300/-  
Faculty members: Rs 500/-

Registration will be done on spot on 19<sup>th</sup> September, 2019 (9.00 AM to 10.00 AM)  
Mode of payment of registration fee: **Cash**

For more details please visit CIC website at <https://cictu.wordpress.com/>

## **Registration form**

**Workshop on Recent Trends of Microscopy: Light To Electron Microscopy & Digital Image Analysis  
19 - 20 September 2019**

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**Name:**

**Designation:**

**Affiliation:**

**Name of the Supervisor (for student only):**

**Address for communication:**

**Mobile No:**

**Email Id:**

**Signature of the participants**

**Signature of Supervisor**  
(for student only)

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